

ABSTRACT OF THE DISCLOSURE

5 A wafer-shipping device and a wafer storage method for protecting
bonding pads from fluoridation. First, at least one through hole is
drilled in the shipping box . The wafer is then placed in the shipping
box. A packaging bag containing the shipping box is put into a vacuum
packaging machine to remove air from the packaging bag and the shipping
box. A dry inert gas is then introduced into the packaging bag and
the shipping box until approaching atmospheric pressure as so to
10 prevent the shipping box from collapse. The packaging bag is then
sealed.